

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

PRIORITY Application Serial No.09/653,157
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Assignee..... Micron Technology, Inc.
PRIORITY Group Art Unit..... 1765
PRIORITY Examiner Deo, Duy Vu Nguyen
Attorney's Docket No.MI22-2559
Title: Methods of Removing Material from a Semiconductor Substrate (as amended)

AMENDMENT ACCOMPANYING CONTINUATION APPLICATION FILING

To: MS Patent Application
Commissioner for Patents
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AMENDMENTS

Introductory Comments

The preliminary amendment accompanies filing of a continuation application.
Applicant amends the application and remarks as follows.